

Conceptual raytracing for the X-FEL diagnostic monochromators-spectrometers

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Undulator commissioning K-Monochromator (Jens Rehanek)

Single-shot spectrometer (Alexei Erko) dispersive crystal design reflection zone plate (RZP) design





K-Monochromator design concept







Simulate Optical systems up to 10 elements (F. Schäfers) Beamline design tool Geometric Optics

Sources

- Point
- Dipole
- Undulator

RAY

- External source file

Optical elements

- Reflection Mirrors
- Crystals (graded)
- Gratings (VLS)
- Transmission zone plates
- Reflection zone plates



EuroXFEL undulator parameters



Electron source parameters

 $\sigma_x = \sigma_z = 34 \ \mu m$ $\sigma'_x = \sigma'_z = 1 \ \mu rad$

Photon Source Size =
$$\sqrt{\sigma_{x,z}^2 + \sigma_u^2}$$

Source divergence = $\sqrt{\sigma_{x,z}^{'2} + \sigma_u^{'2}}$

Undulator radiation*

$$\sigma_{\rm U} = \frac{\sqrt{2\lambda L}}{2\pi}, \sigma'_{\rm U} = \sqrt{\lambda/2L}$$

1 undulator segment L= 5 m

Electron beam parameters:

Electron energy:	14 GeV
Emittance:	0.97 mm mrad
Beta function:	32 m
Period length:	40 mm
No. periods:	125
Gap-range:	10-28 mm



* Onuki, Elleaume:Wigglers Undulators and their application, Tylor and Francis 2003, page 79

Undulator radiation properties



Radiation field (450 m after source point)





0.5 m after K-Mono







Crystals: 2 x Si 111 (333) channel-cut monochromators

Energy range: 2 – 20 keV

Energy resolution:

photon energy (keV)	∆E (eV)	ΔE / E
5	0.49	1x10 ⁻⁴
10	1.2	1x10 ⁻⁴
	0.065	6.5x10 ⁻⁶
20	2.3	1x10 ⁻⁴
	0.104	5x10 -6







Precise K-parameter measurements





"Gaussian fit method"

E _{ph1} = 12400 eV	Center @ K = 2.34649
E _{ph2} = 12410 eV	Center @ K = 2.34519
∆E/E = 8x10 ⁻⁴	∆K/K = 5x10 ⁻⁴



Motivation

- Typical SASE Single Shot Spectrum



intensity at one wavelength varies from pulse to pulse significantly

wavelength spectrum varies considerably



top view









- \succ resolution: $\Delta E = 30 \text{ meV} / 0.1 \text{ mm}$
- > dispersion: 300 meV / mm (0.5 eV/mrad)
- **FWHM:** 16.5 meV (55μm)
- slope errors: < 1.0 arcsec (state of the art: 0.3 arcsec)



picture: Yabashi et.al., "Single-Shot Spectrometry for X-Ray Free-Electron Lasers", Phys.Rev.Lett. 97, 084802 (2006)

FIG. 3. Spatial profile of dispersed beam (lower axis). The corresponding energy scale is shown on the upper axis.



Reflection Zone Plate Single - Shot Monochromator



Motivation



- X-ray laser is a source of coherent short-pulse radiation. Each optical element in the beam transport line will induce absorption, scattering, distortion etc. Normally, after interaction with 5 7 mirrors, the absorption reduces the flux by several orders of magnitude. Scattering and speckle formation processes will destroy all unique properties of the laser beam. Coherent experiments are very problematic.
- If a radiation of 1000 eV is reflected by 7 mirrors with Au coating, only 1.7 % of the radiation will go though the optics.
- X-ray lasers require new non-traditional solutions and nonconventional designs to ensure that their unique properties can be fully exploited.



Reflection zone plate (2D VLS)





Wavelength range: 0.025 nm (50 keV) – 200 μ m (0.062 eV) Efficiency: 5% - 30 % Energy resolution $\lambda / \Delta \lambda$: 100 – 50 000



RZP applications at BESSY II





5 keV - 16 keV

Bragg-Fresnel Lens on the second monochromator crystal at MySpot beamline 10 eV – 60 eV

Total reflection zone plate as monocromatorspectrometer at HHG harmonic selector





0.5 keV – 1.2 keV

Total reflection zone plate as monocromatorspectrometer at Slicing beamline

6.2 10-³ eV

Total reflection zone plate as monocromatorspectrometer at THz beamline



Parallel X-ray Fluorescence Spectrometer

One pulse, one spectrum: Ultra-fast X-ray spectroscopy spectroscopy

A. Erko, et al., Novel parallel vacuum ultra-violet/X-ray fluorescence spectrometer, Spectrochim. Acta Part B (2012), doi:10.1016/j.sab.2012.01.001



mholtz

Zentrum Berlin



New generation: tests at RIXS beamline











E = 1 keV, E/ Δ E= 40 000 (25 meV at 1 keV), Detector pixel size = 20 μ m





Beam parameters at 253 m

λ/E	Beam size D	∆t
1.24nm (1keV)	~7 mm	< 100 fs

$$\Delta t = \frac{\lambda}{c} N$$

Diffraction structure parameters

L	α	β	d	Δx	$\lambda/\Delta\lambda$	2 0	R ₁	R ₂
155mm	0.2° (3.5 mrad)	1.18°	6.2 μm (160 l/mm)	20µm	25000	1.38°	253m	80m

Reflection zone plate parameters

γ	r ₁ r ₂		δ x _{min}	
0.4 4°	116.2 m	216.8 m	10.8 µm	



Single-Shot monochromator position SASE3







E = 10 keV, E/ Δ E= 30 000 (0.33 eV at 10 keV), Detector pixel size = 20 μ m





Beam parameters at 310 m

λ/E	Beam size
0.124nm (10 keV)	~ 1 mm

 $\Delta t_{N} \sim 4.1 \ 10^{-19} \text{ s, at } 0.124 \text{ nm}$ N ~ 30000

Diffraction structure parameters

α	β	d	$\lambda/\Delta\lambda$	2 0	R ₁	R ₂
0.1° (1.75 mrad)	0.37°	6.4 μm (156 l/mm)	30000 0.33 eV	0.47 °	310 m	200 m

Reflection zone plate parameters

L	γ	r ₁	r ₂	δ x _{min}	Δt	∆x detector resolution
200 mm (400 mm)	0.2 °	144 m	356 m	10.8 µm	~ 12 fs (25 fs)	20µm

Single-Shot monochromator position SASE 2









We propose minimizing the number of optical elements in the beamline by combining reflection, focusing and dispersion in one single element. We considerably increase efficiency (20 times in the example of the BESSY II Slicing beamline), reduce scattering and slope errors using flat substrates and PRESERVE COHERENCE.

Reflection zone plates have been experimentally tested in the energy range 0.062 eV to 20 keV at several BESSY II beamlines and show high stability, efficiency and energy resolution.

The radiation stability tests are necessary to confirm advantages of reflection zone plates in XFEL applications.











Thank you!